Amendments to the Claims:

This listing of claims will replace all prior versions and listings of claims in the application:

Listing of Claims

1. (currently amended) A large profile, high speed laser micrometer, comprising:

(a) a light source unit ~~comprised of an~~ having at least one emitter module that emits a laser sheet, said emitter module having a plurality of laser line generators arranged in overlapping fashion to prevent gaps in the laser sheet;

(b) a detector array ~~comprised of~~ having at least one detector module having a plurality of detectors arranged in overlapping fashion, wherein said emitter module and said detector module are aligned; and

(c) at least one data processing unit coupled to said detector array;

such that dimensions of an object passing between said light source unit and said detector array can be measured ~~to an accuracy of at least 4/100ths of an inch.~~

2. (canceled)

3. (currently amended) The laser micrometer according to claim ~~2~~ 1, wherein one or both of said laser line generators and said detectors are arranged in an ~~overlapping~~ stair-step fashion.

4. (currently amended) The laser micrometer according to claim ~~2~~ 1, wherein said detector module is comprised of ~~one or more~~ linear CIS detectors, the number of said linear CIS

detectors equal to the number of laser line generators~~, said linear CIS detectors arranged in an overlapping fashion corresponding to said laser line generators.~~

5. (currently amended) A large profile, high speed laser micrometer, comprising:

(a) a light source unit ~~comprised of~~ having a plurality of emitter modules that combine to emit a laser sheet, each of said emitter modules having a plurality of laser line generators arranged in an overlapping fashion to prevent gaps in the laser sheet;

(b) a detector array ~~comprised of~~ having a plurality of detector modules, each of said detector modules having a plurality of detectors arranged in an overlapping fashion to prevent gaps in the laser sheet, wherein each of said plurality of emitter modules and each of said plurality of detector modules are aligned; and

(c) one or more data processing units coupled to said detector array;

such that dimensions of an object passing between said light source unit and said detector array can be measured ~~to an accuracy of at least 4/100ths of an inch.~~

6. (canceled)

7. (currently amended) The laser micrometer according to claim ~~6~~ 5 wherein one or both of said laser line generators and said detectors are arranged in ~~an overlapping~~ stair-step fashion.

8. (currently amended) The laser micrometer according to claim ~~6~~ 5, wherein each of said detector modules is comprised of ~~two or more~~ linear CIS detectors, the number of said linear CIS detectors equal to the number of laser line generators~~,said linear CIS detectors arranged in an overlapping stair step fashion corresponding to said laser line generators~~.

9. (original) The laser micrometer according to claim 5, wherein the number of data processing units is equal to a fraction of the number of said detector modules such that each data processing unit provides data processing for a number of detector modules located adjacent to one another.

10. (original) The laser micrometer according to claim 9, where said fraction is one-third.

11. (Withdrawn) An apparatus for emitting a linear, planar sheet of light, comprising:

(a) a laser which emits a beam of light;

(b) an aspherical lens which converts said beam of light into a fan-shaped sheet of light; and

(c) a parabolic mirror which reflects said fan-shaped sheet of light into a linear, planar sheet of light.

12. (Withdrawn) The apparatus according to claim 11, further comprising a flat mirror located between said aspherical lens and said parabolic mirror which reflects said fan-shaped sheet of light from said aspherical lens into said parabolic mirror.